


To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner initialed copy of this form be returned to the undersigned.

Respectfully submitted,

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Date 3-2-05

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FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

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Complete if Known

Application Number	10/709,622
Filing Date	May 18, 2004
First Named Inventor	Hiroshi Nogami
Examiner Name	JEFFRIE ROBERT LUND
Attorney Docket Number	001425-126

U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
	5,449,410		Chang et al.	09-12-1995
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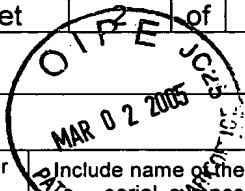
Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	STATUS						
					Translation	Partial Translation	Eng. Lang. Summary	Search Report	IPER	Abstract	Cited in Spec
	7-201749		Japan	08-04-1995							
	2837087		Japan	10-09-1998							
	6-260434		Japan	09-16-1994						X	
	5-21393		Japan	01-29-1993						X	

Examiner Signature

Date Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

Substitute for form 1449A/PTO & 1449B/PTO		Complete if Known		
FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/709,622	
		Filing Date	May 18, 2004	
		First Named Inventor	Hiroshi Nogami	
		Examiner Name	JEFFRIE ROBERT LUND	
Sheet	of	2	Attorney Docket Number	001425-126



NON-PATENT LITERATURE DOCUMENTS	
Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	Shingo KADOMURA et al., "ANISOTROPIC ETCHING USING DEPOSITION OF SULFUR, Sony Corporation, Semiconductor World, January 1993, pp. 1-11, and translation
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	A new technique for diagnostics of a radio-frequency parallel-plate remote plasma; N. Sano et al.; Appl. Phys. Lett 65 (2), 11 July 1994 pages 162-164.
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Examiner Signature	Date Considered
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